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PATENT APPLICATION

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SMA  
12/31/02

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q63075

Kazunobu FUJIKAWA, et al.

Appln. No.: 09/763,194

Group Art Unit: 1725

Confirmation No.: 3832

Examiner: Maria Alexandra ELVE

Filed: February 20, 2001

For: METHOD AND APPARATUS FOR SURFACE DISCHARGE PROCESSING, AND AN ELECTRODE FOR SURFACE DISCHARGE PROCESSING

AMENDMENT UNDER 37 C.F.R. § 1.111

Commissioner for Patents  
Washington, D.C. 20231

Sir:

In response to the Office Action dated September 11, 2002, please amend the above-identified application as follows:

IN THE CLAIMS:

Please enter the following amended claims:

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6. (Amended) A surface discharge processing apparatus which generates an electric discharge between an electrode and a workpiece thereby forming a surface reforming layer on the surface of said workpiece, said surface discharge processing apparatus comprising:

a wire electrode as said electrode; and

a wire electrode feeder which feeds said wire electrode to said workpiece during surface discharge processing,